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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 7391
Tatsuya SASAKI et al. : Attorney Docket No. 2005_1908A
Serial No. 10/559,815 : Group Art Unit 1792
Filed March 23, 2006 : Examiner Sylvia MacArthur

POLISHING APPARATUS
AND POLISHING METHOD

RESPONSE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

Pursuant to the requirement contained in the Office Action mailed November 14, 2008, Applicants hereby elect invention II, claims 5-8, drawn to a polishing method.

In view of this election, a full examination on the merits of the present application is respectfully requested.

Respectfully submitted,

Tatsuya SASAKI et al.

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December 8, 2008